

**Search Notes**

Application No.

10/600,393

Examiner

Toniae M. Thomas

Applicant(s)

CHEN ET AL.

Art Unit

2822

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**SEARCHED**

Class	Subclass	Date	Examiner
438	275	9/10/2004	TMT
"	770-777	9/10/2004	"
"	787-788	9/10/2004	"
438	791-792	9/10/2004	TMT
updated	all above	3/18/2005	TMT

**INTERFERENCE SEARCHED**

Class	Subclass	Date	Examiner

**SEARCH NOTES  
(INCLUDING SEARCH STRATEGY)**

	DATE	EXMR
USPAT US PG-Pub	9/10/2004	TMT
USPAT US PG-Pub	9/9/2004	TMT
USPAT US PG-Pub	9/8/2004	TMT
NPL database (silicon nitride and (atomic layer chemical vapor deposition or atomic layer deposition)	9/10/2004	TMT
NPL (silicon nitride and remote plasma enhanced chemical vapor deposition	9/10/2004	TMT